

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L4	35829	semiconductor same manufactur\$4 same process same substrate	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:46
L5	10937	semiconductor same manufactur\$4 same process same substrate same material	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:46
L6	6050	semiconductor same manufacturing with process same substrate same material	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:46
L7	3648	semiconductor with manufacturing with process same substrate same material	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:47
L8	2594	semiconductor with manufacturing with process same substrate with material	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:47
L9	1365	semiconductor with manufacturing with process with substrate with material	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:47
L10	12	semiconductor with manufacturing with process with substrate with material same detector	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:50
L11	15	semiconductor with manufacturing with process with substrate with material and detector same gas	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:53
L12	0	semiconductor with manufacturing with process with substrate with material and detector same gas same x-ray	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:54
L13	0	semiconductor with manufacturing with process with substrate same material same detector same gas same x-ray	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:54
L14	0	semiconductor with manufacturing with process with substrate same detector same gas same x-ray	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:54

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L15	0	semiconductor with manufacturing with process with substrate and detector same gas same x-ray	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 13:56
L16	81	semiconductor with substrate and detector same gas same x-ray	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 14:07
L17	1	"6121622".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:04
L18	1	"5731584".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:05
L19	1	"5349194".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:05
L20	1	"5731584".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:05
L21	1	"5614722".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:05
L22	1	"5602397".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:06
L23	1	"5349194".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:06
L24	1	"5308987".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:06
L25	1	"5602397".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:06
L26	1	"5032729".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:06
L27	1	"4376892".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:07
L28	45	semiconductor with substrate and detector same gas same x-ray and chamber	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 14:21
L29	1	"4980553".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:13
L30	1	"4891522".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:14
L31	1	"4940901".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:14
L32	1	"4419696".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:15
L33	1	"4755880".PN.	USPAT; USOCR	OR	ON	2006/03/28 14:15

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L34	4	semiconductor with substrate same detector same gas same x-ray and chamber	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 14:29
L35	1	"6362484" and computer\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 14:36
L36	19	"3418474"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 14:37
L37	13	"4780897"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2006/03/28 14:38